

Title (en)  
METHOD AND APPARATUS FOR PLASMA GENERATION

Title (de)  
VERFAHREN UND VORRICHTUNG ZUR PLASMAERZEUGUNG

Title (fr)  
PROCEDE ET APPAREIL DE GENERATION DE PLASMA

Publication  
**EP 1656688 A2 20060517 (EN)**

Application  
**EP 04778627 A 20040719**

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Abstract (en)  
[origin: WO2005017943A2] An RF-driven plasma source, including a pair of spaced-apart plasma electrodes, wherein the electrodes act as plates of a capacitor, the gas electrically discharges and creates a plasma of both positive and negative ions, in a clean process that enables efficient sample analysis, with preferred isolated sample photo-ionization, reduced-power operation and also including signal detection with modulated drive electronics.

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